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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of: **Tetsuo FUKUDA, et al.**

Group Art Unit: **Not Yet Assigned**

Serial No.: **Not Yet Assigned**

Examiner: **Not Yet Assigned**

Filed: **June 27, 2003**

For: **SEMICONDUCTOR SUBSTRATE AND METHOD FOR FABRICATING THE SAME**

CLAIM FOR PRIORITY UNDER 35 U.S.C. 119

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Date: June 27, 2003

Sir:

The benefit of the filing dates of the following prior foreign applications are hereby requested for the above-identified application, and the priority provided in 35 U.S.C. 119 is hereby claimed:

Japanese Appln. No. 2002-192133, filed July 1, 2002

In support of this claim, the requisite certified copies of said original foreign applications are filed herewith.

It is requested that the file of this application be marked to indicate that the applicants have complied with the requirements of 35 U.S.C. 119 and that the Patent and Trademark Office kindly acknowledge receipt of said certified copies.

In the event that any fees are due in connection with this paper, please charge our Deposit Account No. 01-2340.

Respectfully submitted,

ARMSTRONG, WESTERMAN & HATTORI, LLP



Donald W. Hanson
Attorney for Applicants
Reg. No. 27,133

DWH/jaz
Atty. Docket No. **030766**
Suite 1000
1725 K Street, N.W.
Washington, D.C. 20006
(202) 659-2930



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